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L1	1	10/658168	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:58
L2	3	knoch-john$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:58
L3	1	leek-deborah$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L4	2	strader-nathan$.in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L5	7328	LSI with logic$.as.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 10:59
L10	127	L5 and wafer and (process$3 with tool)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:02
L11	1	((pre-scan prescan) same defect) and wafer and (process$3 with tool) and ((post-scan postscan) same defect) and (display$3 same scatter same plot).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:04
L12	341	702/81.ccls.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:05
L13	4	((pre-scan prescan post-scan postscan) same defect) and wafer and (process$3 with tool)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/10 11:04

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